PHYSICS OF NANOELECTRONIC MATERIALS GROUP

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EQUIPMENT

SCANNING ELECTRON MICROSCOPE (SEM)

HITACHI S-2500

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EQUIPMENT

SCANNING ELECTRON MICROSCOPE (SEM)

LEO-LEICA Stereoscan 440

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EQUIPMENT

SCANNING ELECTRON MICROSCOPE

FEI INSPEC - S

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CHARACTERIZATION TECHNIQUES IMPLEMENTED IN SEM

CATHODOLUMINESCENCE (CL) - VISIBLE AND NIR RANGES

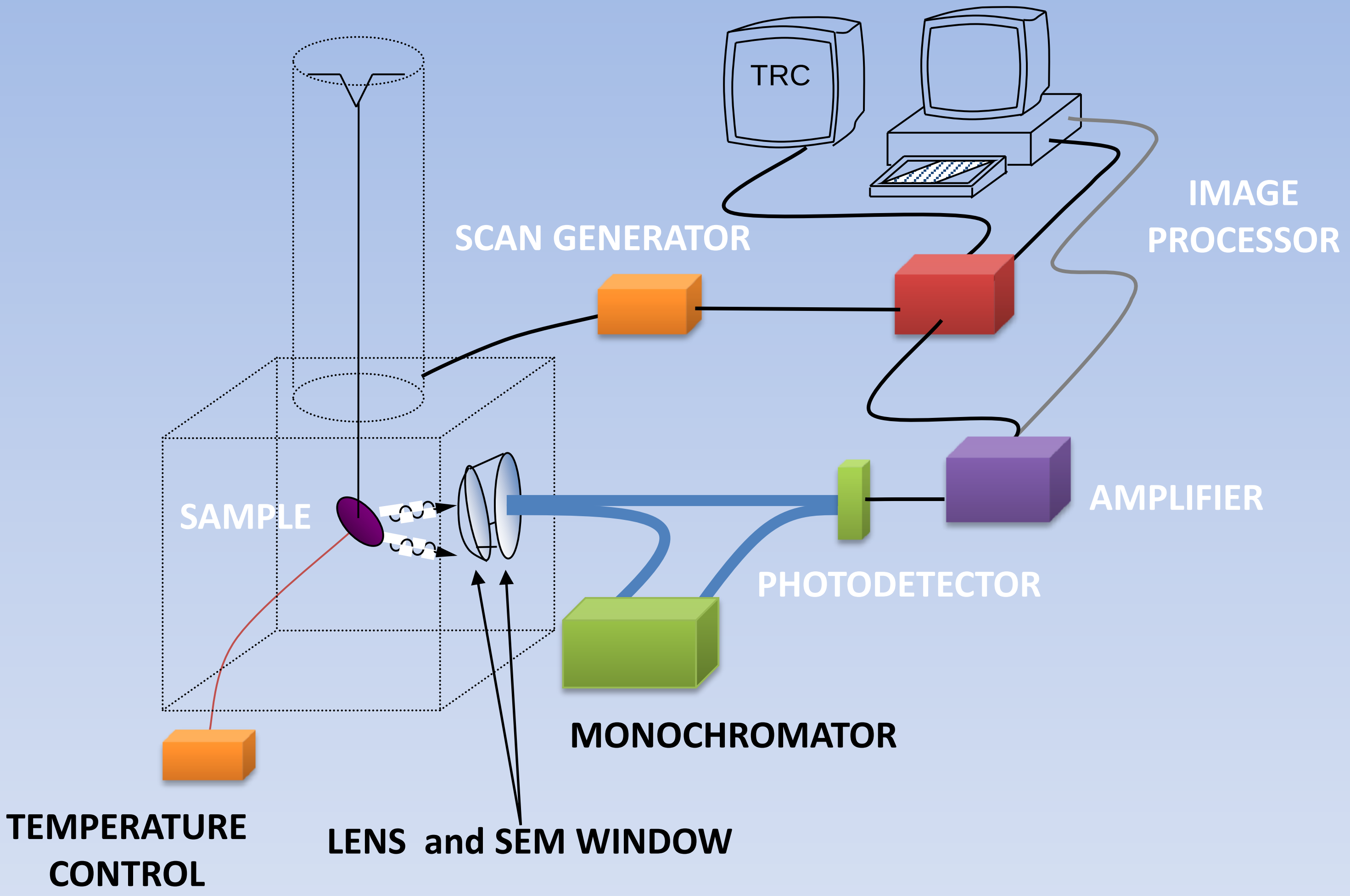
TIME RESOLVED CATHODOLUMINESCENCE (TR-CL)

ELECTRON BEAM INDUCED CURRENT (EBIC)

X-RAY MICROANALYSIS BY ENERGY DISPERSIVE SPECTROSCOPY (EDS)

FIELD-EMISSION MEASUREMENTS

CATHODOLUMINESCENCE -SEM



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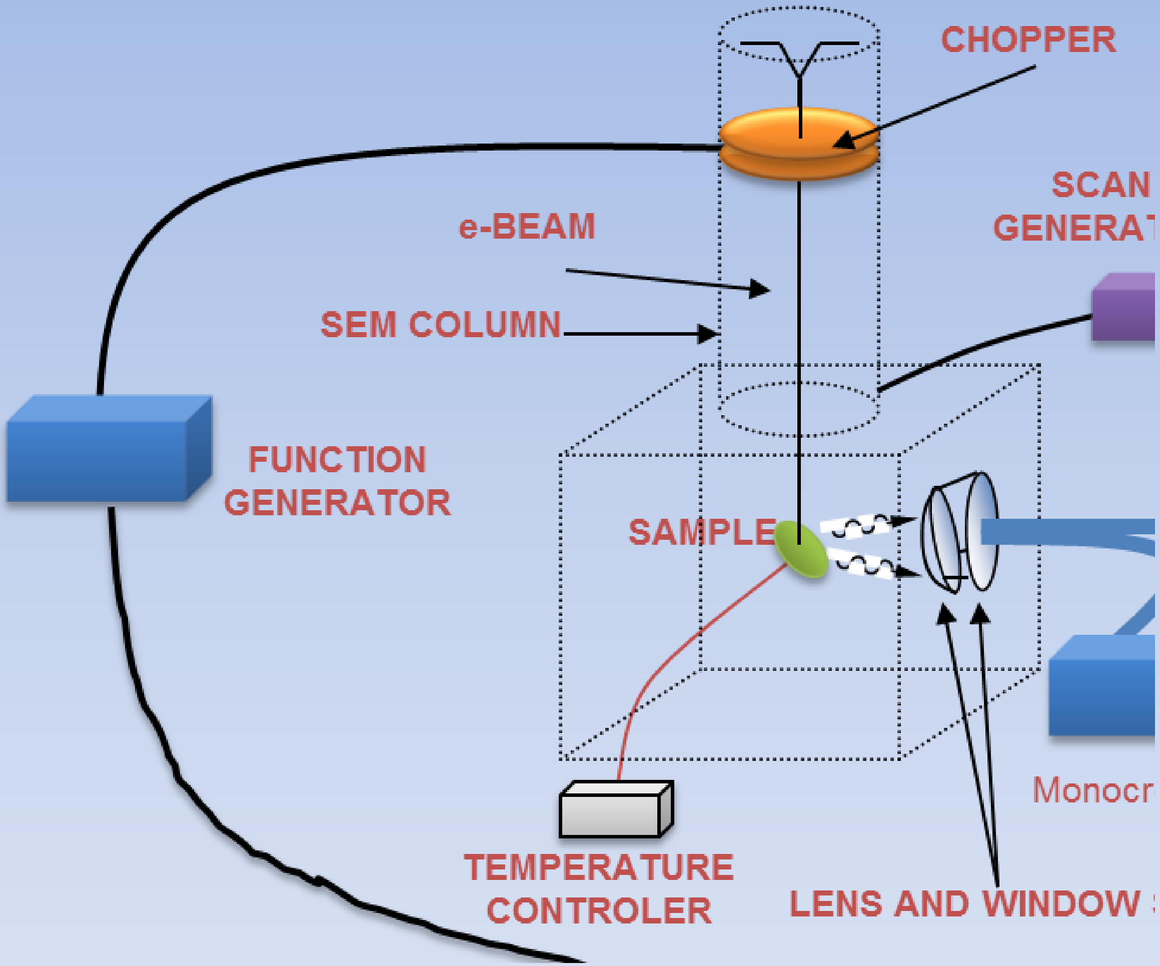
TIME-RESOLVED -CL



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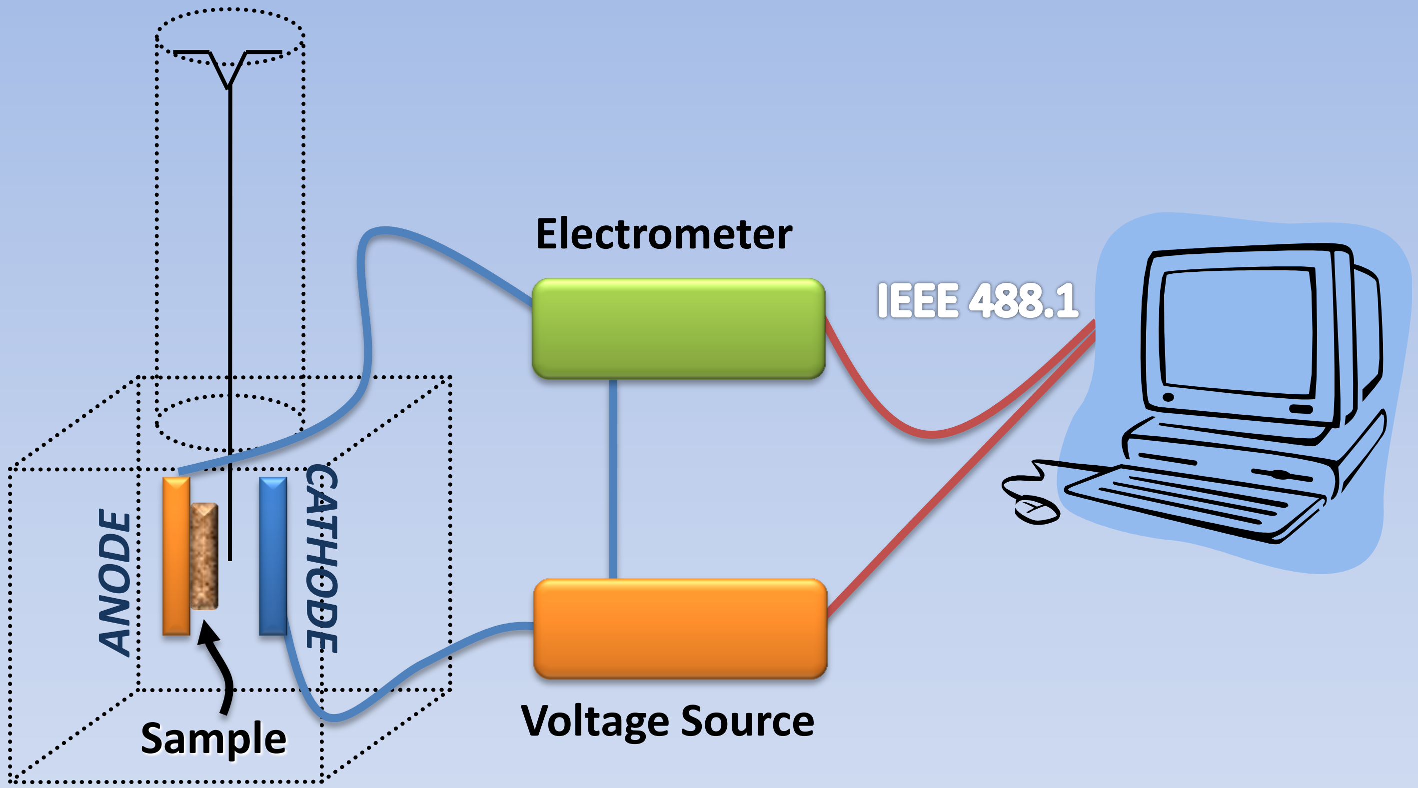
FIELD EMISSION MEASUREMENTS IN SEM



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AFM

NANOTEC - *Cervantes AFM System*

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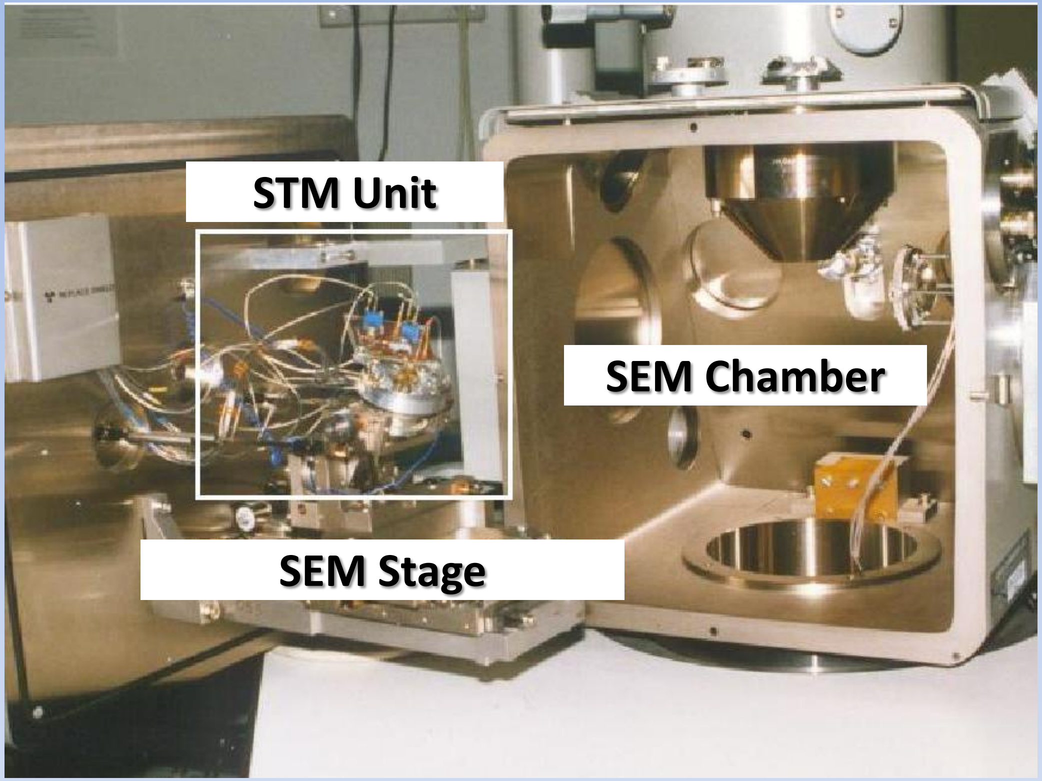
STM in SEM chamber (Nanotec)

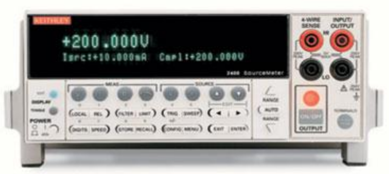


CONFOCAL LASER MICROSCOPE (micro-PL and micro-RAMAN)

Confocal Microscope- Horiba Jobin-Yvon LabRam HR800
He-Cd 365 nm laser

Electrical characterization (ρ, I-V, C-V, C-f, ..)

SOURCE-METER
KEITHLEY 2400



CURRENT AMPLIFIER
KEITHLEY 428

ELECTROMETER
KEITHLEY 6514

LCR BRIDGE
TEGAM 2610

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FURNACES UP TO 1500 ºC